

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Yuichi SHIBAZAKI

Application No.: 10/588,029

Filed: August 1, 2006

Docket No.: 127874

For: STAGE DRIVE METHOD AND STAGE UNIT, EXPOSURE APPARATUS, AND DEVICE MANUFACTURING METHOD

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

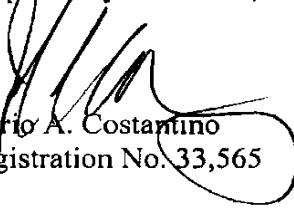
Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- 2. Relevance of one or more non-English language reference is discussed in the present specification. See Reference 186.
- 3. One or more reference cited herein was cited in the International Search Report. A copy of the International Search Report is attached for the Examiner's information. See References 191-194.
- 4. In accordance with 37 CFR §1.98(a)(2)(ii), copies of any U.S. patents and patent application publications are not attached.
- 5. An English language Abstract of one or more non-English language reference is attached hereto. See References 186 and 189-208.

- 6. A computer-generated English language translation of one or more Japanese Patent Publication cited herein has been obtained from the website of the Japanese Patent Office ([<http://www.jpo.go.jp>]), and is attached, but has not been reviewed for accuracy. See References 191-193 and 199.
- 7. An English language translation of one or more Patent Publication cited herein has been obtained and is attached, but has not been reviewed for accuracy. See References 186, 189, 190, 194, 197, 198 and 200-208.
- 8. Reference 184 corresponds to reference 191. Reference 187 corresponds to reference 192. Reference 188 corresponds to reference 193.

Respectfully submitted,


Mario A. Costantino
Registration No. 33,565

Joel S. Armstrong
Registration No. 36,430

MAC:JSA/jtp

Date: January 4, 2007

OLIFF & BERRIDGE, PLC
P.O. Box 19928
Alexandria, Virginia 22320
Telephone: (703) 836-6400

DEPOSIT ACCOUNT USE
AUTHORIZATION
Please grant any extension
necessary for entry;
Charge any fee due to our
Deposit Account No. 15-0461

Form PTO-1449 (REV. 1/06)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 127874	APPLICATION NO. 10/588,029
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)				APPLICANT Yuichi SHIBAZAKI	
				FILING DATE August 1, 2006	
U.S. PATENT DOCUMENTS					
Examiner Initials	Cite No.	Document Number	Date	Name	
	1.	2005/0190455 A1	09/01/2005	ROSTALSKI et al.	
	2.	2005/0117224 A1	06/02/2005	SHAFER et al.	
	3.	2002/0163629 A1	11/07/2002	SWITKES et al.	
	4.	2003/0030916 A1	02/13/2003	SUENAGA	
	5.	2005/0141098 A1	06/30/2005	SCHUSTER	
	6.	2004/0000627 A1	01/01/2004	SCHUSTER	
	7.	2005/0030506 A1	02/10/2005	SCHUSTER	
	8.	2005/0217135 A1	10/06/2005	O'DONNELL et al.	
	9.	2005/0217137 A1	10/06/2005	SMITH et al.	
	10.	2005/0217703 A1	10/06/2005	O'DONNELL	
	11.	2004/0075895 A1	04/22/2004	LIN	
	12.	2004/0118184 A1	06/24/2004	VIOLETTE	
	13.	2004/0125351 A1	07/01/2004	KRAUTSCHIK	
	14.	2004/0180294 A1	09/16/2004	BABA-ALI et al.	
	15.	2004/0169924 A1	09/02/2004	FLAGELLO et al.	
	16.	2004/0227923 A1	11/18/2004	FLAGELLO et al.	
	17.	2003/0174408 A1	09/18/2003	ROSTALSKI et al.	
	18.	2004/0180299 A1	09/16/2004	ROLLAND et al.	
	19.	2004/0109237 A1	06/10/2004	EPPLER et al.	
FOREIGN PATENT DOCUMENTS					
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract With English Translation
OTHER DOCUMENTS					
Examiner Initials	Cite No.	(Including Author, Title, Date, Pertinent Pages, etc.)			
EXAMINER				DATE CONSIDERED	
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.					

Form PTO-1449 (REV. 1/06)	US Dept. of Commerce PATENT & TRADEMARK OFFICE	ATTY DOCKET NO. 127874	APPLICATION NO. 10/588,029
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)		APPLICANT Yuichi SHIBAZAKI	
		FILING DATE August 1, 2006	

U.S. PATENT DOCUMENTS				
Examiner Initials	Cite No.	Document Number	Date	Name
	20.	2004/0257544 A1	12/23/2004	VOGEL et al.
	21.	2004/0263808 A1	12/30/2004	SEWELL
	22.	2005/0036183 A1	02/17/2005	YEO et al.
	23.	2005/0036184 A1	02/17/2005	YEO et al.
	24.	2005/0037269 A1	02/17/2005	LEVINSON
	25.	2005/0036213 A1	02/17/2005	MANN et al.
	26.	2004/0224265 A1	11/11/2004	ENDO et al.
	27.	2004/0224525 A1	11/11/2004	ENDO et al.
	28.	2005/0046934 A1	03/03/2005	HO et al.
	29.	2005/0048223 A1	03/03/2005	PAWLOSKI et al.
	30.	2004/0253547 A1	12/16/2004	ENDO et al.
	31.	2004/0253548 A1	12/16/2004	ENDO et al.
	32.	2005/0068639 A1	03/31/2005	PIERRAT et al.
	33.	2005/0073670 A1	04/07/2005	CARROLL
	34.	2005/0084794 A1	04/21/2005	MEAGLEY et al.
	35.	2005/0094116 A1	05/05/2005	FLAGELLO et al.
	36.	2005/0100745 A1	05/12/2005	LIN et al.
	37.	2004/0136494 A1	07/15/2004	LOF et al.
	38.	2004/0160582 A1	08/19/2004	LOF et al.

FOREIGN PATENT DOCUMENTS						
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract	With English Translation

OTHER DOCUMENTS		
Examiner Initials	Cite No.	(Including Author, Title, Date, Pertinent Pages, etc.)

EXAMINER	DATE CONSIDERED
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

Form PTO-1449 (REV. 1/06)		US Dept. of Commerce PATENT & TRADEMARK OFFICE	ATTY DOCKET NO. I27874	APPLICATION NO. 10/588,029
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)		APPLICANT Yuichi SHIBAZAKI		
		FILING DATE August 1, 2006		

U.S. PATENT DOCUMENTS				
Examiner Initials	Cite No.	Document Number	Date	Name
	39.	2004/0165159 A1	08/26/2004	LOF et al.
	40.	2004/0207824 A1	10/21/2004	LOF et al.
	41.	2004/0211920 A1	10/28/2004	MARIA DERKSON et al.
	42.	2005/0036121 A1	02/17/2005	HOOGENDAM et al.
	43.	2004/0169834 A1	09/02/2004	RICHTER et al.
	44.	2004/0259040 A1	12/23/2004	ENDO et al.
	45.	2004/0114117 A1	06/17/2004	BLEEKER
	46.	2004/0259008 A1	12/23/2004	ENDO et al.
	47.	2005/0110973 A1	05/26/2005	STREEFKERK et al.
	48.	2005/0122497 A1	06/09/2005	LYONS et al.
	49.	2004/0119954 A1	06/24/2004	KAWASHIMA et al.
	50.	2005/0185269 A1	08/25/2005	EPPEL et al.
	51.	2005/0225737 A1	10/13/2005	WEISSENRIEDER et al.
	52.	2005/0132914 A1	06/23/2005	MULKENS et al.
	53.	2005/0134815 A1	06/23/2005	VAN SANTEN et al.
	54.	2005/0147920 A1	07/07/2005	LIN et al.
	55.	2005/0145803 A1	07/07/2005	HAKEY et al.
	56.	2005/0146694 A1	07/07/2005	TOKITA
	57.	2005/0146695 A1	07/07/2005	KAWAKAMI

FOREIGN PATENT DOCUMENTS						
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract	With English Translation

OTHER DOCUMENTS		
Examiner Initials	Cite No.	(Including Author, Title, Date, Pertinent Pages, etc.)

EXAMINER	DATE CONSIDERED
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

Form PTO-1449 (REV. 1/06)	US Dept. of Commerce PATENT & TRADEMARK OFFICE	ATTY DOCKET NO. 127874	APPLICATION NO. 10/588,029
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)		APPLICANT Yuichi SHIBAZAKI	
		FILING DATE August 1, 2006	

U.S. PATENT DOCUMENTS				
Examiner Initials	Cite No.	Document Number	Date	Name
	58.	2005/0153424 A1	07/14/2005	COON
	59.	2005/0190435 A1	09/01/2005	SHAFER et al.
	60.	2005/0158673 A1	07/21/2005	HAKEY et al.
	61.	2005/0164502 A1	07/28/2005	DENG et al.
	62.	2005/0270505 A1	12/08/2005	SMITH
	63.	2005/0174549 A1	08/11/2005	DUINEVELD et al.
	64.	2005/0175940 A1	08/11/2005	DIERICHS
	65.	2005/0042554 A1	02/24/2005	DIERICHS et al.
	66.	2005/0205108 A1	09/22/2005	CHANG et al.
	67.	2005/0213061 A1	09/29/2005	HAKEY et al.
	68.	2005/0213072 A1	09/29/2005	SCHENKER et al.
	69.	2005/0219499 A1	10/06/2005	MARIA ZAAL et al.
	70.	2005/0219482 A1	10/06/2005	BASELMANS et al.
	71.	2005/0219481 A1	10/06/2005	COX et al.
	72.	2005/0024609 A1	02/03/2005	DE SMIT et al.
	73.	2005/0231694 A1	10/20/2005	KOLESNYCENKO et al.
	74.	2005/0237501 A1	10/27/2005	FURUKAWA et al.
	75.	2005/0245005 A1	11/03/2005	BENSON
	76.	2005/0243292 A1	11/03/2005	BASELMANS et al.
	77.	2005/0253090 A1	11/17/2005	GAU et al.

FOREIGN PATENT DOCUMENTS						
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract	With English Translation

OTHER DOCUMENTS		
Examiner Initials	Cite No.	(Including Author, Title, Date, Pertinent Pages, etc.)

EXAMINER	DATE CONSIDERED
Examiner:	Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Form PTO-1449 (REV. 1/06)		US Dept. of Commerce PATENT & TRADEMARK OFFICE	ATTY DOCKET NO. 127874	APPLICATION NO. 10/588,029
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)		APPLICANT Yuichi SHIBAZAKI		
		FILING DATE August 1, 2006		

U.S. PATENT DOCUMENTS				
Examiner Initials	Cite No.	Document Number	Date	Name
	78.	2005/0007569 A1	01/13/2005	STREEFKERK et al.
	79.	2005/0259232 A1	11/24/2005	STREEFKERK et al.
	80.	2004/0233405 A1	11/25/2004	KATO et al.
	81.	2005/0259233 A1	11/24/2005	STREEFKERK et al.
	82.	2005/0007570 A1	01/13/2005	STREEFKERK et al.
	83.	2005/0264778 A1	12/01/2005	LOF et al.
	84.	2005/0002004 A1	01/06/2005	KOLESNYCHENKO et al.
	85.	2005/0030498 A1	02/10/2005	MULKENS
	86.	2004/0263809 A1	12/30/2004	NAKANO
	87.	2005/0018155 A1	01/27/2005	COX et al.
	88.	2005/0018156 A1	01/27/2005	MULKENS et al.
	89.	2005/0030497 A1	02/10/2005	NAKAMURA
	90.	2005/0134817 A1	06/23/2005	NAKAMURA
	91.	2005/0145265 A1	07/07/2005	RAVKIN et al.
	92.	2005/0041225 A1	02/24/2005	SENGERS et al.
	93.	2005/0046813 A1	03/03/2005	STREEFKERK et al.
	94.	2005/0048220 A1	03/03/2005	MERTENS et al.
	95.	2005/0030511 A1	02/10/2005	AUER-JONGEPIER et al.
	96.	2005/0078286 A1	04/14/2005	DIERICHS et al.
	97.	2005/0078287 A1	04/14/2005	SENGERS et al.

FOREIGN PATENT DOCUMENTS						
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract	With English Translation

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)		
Examiner Initials	Cite No.	

EXAMINER	DATE CONSIDERED
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

Form PTO-1449 (REV. 1/06) INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)			US Dept. of Commerce PATENT & TRADEMARK OFFICE	ATTY DOCKET NO. I27874	APPLICATION NO. 10/588,029
			APPLICANT Yuichi SHIBAZAKI		
			FILING DATE August 1, 2006		
U.S. PATENT DOCUMENTS					
Examiner Initials	Cite No.	Document Number	Date	Name	
	98.	2005/0233081 A1	10/20/2005	TOKITA	
	99.	2005/0052632 A1	11/10/2005	MIYAJIMA	
	100.	2005/0088635 A1	4/28/2005	HOOGENDAM et al.	
	101.	2005/0259236 A1	11/24/2005	STRAAIJER	
	102.	2005/0094114 A1	5/5/2005	STREEFKERK et al.	
	103.	2005/0094119 A1	5/5/2005	LOOPSTRS et al.	
	104.	2005/0074704 A1	4/7/2005	ENDO et al.	
	105.	2005/0179877 A1	8/18/2005	MULKENS et al.	
	106.	2005/0174550 A1	8/11/2005	STREEFKERK et al.	
	107.	2005/0263068 A1	12/1/2005	HOOGENDAM et al.	
	108.	2005/0106512 A1	5/19/2005	ENDO et al.	
	109.	2005/0117135 A1	6/2/2005	VERHOEVEN et al.	
	110.	2005/0175776 A1	8/11/2005	STREEFKERK et al.	
	111.	2005/0122505 A1	6/9/2005	MIYAJIMA	
	112.	2005/0146693 A1	7/7/2005	OHSAKI	
	113.	2005/0136361 A1	6/23/2005	ENDO et al.	
	114.	2006/0114445 A1	6/1/2006	EBIHARA	
	115.	2006/0132733 A1	6/22/2006	MODDERMAN	
	116.	2006/0126037 A1	6/15/2006	JANSEN et al.	
FOREIGN PATENT DOCUMENTS					
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract With English Translation
OTHER DOCUMENTS					
Examiner Initials	Cite No.	(Including Author, Title, Date, Pertinent Pages, etc.)			
EXAMINER				DATE CONSIDERED	
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.					

Form PTO-1449 (REV. 1/06)			US Dept. of Commerce PATENT & TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)		ATTY DOCKET NO. 127874		APPLICATION NO. 10/588,029	
					APPLICANT Yuichi SHIBAZAKI			
					FILING DATE August 1, 2006			
U.S. PATENT DOCUMENTS								
Examiner Initials	Cite No.	Document Number	Date	Name				
	117.	2006/0103820 A1	5/18/2006	DONDERIS et al.				
	118.	2006/0082741 A1	4/20/2006	VAN DER TOORN et al.				
	119.	2006/0094125 A1	5/4/2006	SINGH et al.				
	120.	2005/0128445 A1	6/16/2005	HOOGENDAM et al.				
	121.	4,346,164	8/24/1982	TABARELLI et al.				
	122.	4,480,910	11/6/1984	TAKANASHI et al.				
	123.	5,610,683	3/11/1997	TAKAHASHI				
	124.	5,715,039	2/3/1998	FUKUDA et al.				
	125.	5,825,043	10/20/1998	SUWA				
FOREIGN PATENT DOCUMENTS								
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract	With English Translation		
	126.	WO 2002/091078 A1	11/14/2002	WIPO				
	127.	WO 2004/077154 A2	09/10/2004	WIPO				
	128.	WO 2003/077037 A1	09/18/2003	WIPO				
	129.	WO 2004/081666 A1	09/23/2004	WIPO				
	130.	WO 2005/001432 A2	01/06/2005	WIPO				
	131.	WO 2004/093159 A2	10/28/2004	WIPO				
	132.	WO 2004/090634 A2	10/21/2004	WIPO				
	133.	WO 2004/090633 A2	10/21/2004	WIPO				
	134.	WO 2004/092833 A2	10/28/2004	WIPO				
	135.	WO 2004/093160 A2	10/28/2004	WIPO				
	136.	WO 2004/090577 A2	10/21/2004	WIPO				
OTHER DOCUMENTS								
Examiner Initials	Cite No.	(Including Author, Title, Date, Pertinent Pages, etc.)						
EXAMINER						DATE CONSIDERED		
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								

Form PTO-1449 (REV. 1/06)			US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 127874		APPLICATION NO. 10/588,029	
INFORMATION DISCLOSURE STATEMENT <small>(Use several sheets if necessary)</small>								
			APPLICANT Yuichi SHIBAZAKI					
			FILING DATE August 1, 2006					
U.S. PATENT DOCUMENTS								
Examiner Initials	Cite No.	Document Number	Date	Name				
FOREIGN PATENT DOCUMENTS								
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract	With English Translation		
	137.	WO 2004/092830 A2	10/28/2004	WIPO				
	138.	WO 2004/093130 A2	10/28/2004	WIPO				
	139.	WO 2004/095135 A2	11/04/2004	WIPO				
	140.	WO 2005/003864 A2	01/13/2005	WIPO				
	141.	WO 2005/006026 A2	01/20/2005	WIPO				
	142.	WO 2005/008339 A2	01/27/2005	WIPO				
	143.	WO 2005/013008 A2	02/10/2005	WIPO				
	144.	WO 2005/017625 A2	02/24/2005	WIPO				
	145.	WO 2005/015283 A1	02/17/2005	WIPO				
	146.	WO 2005/019935 A2	03/03/2005	WIPO				
	147.	WO 2005/024325 A2	03/17/2005	WIPO				
	148.	WO 2005/022266 A2	03/10/2005	WIPO				
	149.	WO 2005/024517 A2	03/17/2005	WIPO				
	150.	WO 2005/034174 A2	04/14/2005	WIPO				
	151.	WO 2004/055803 A1	07/01/2004	WIPO				
	152.	WO 2004/057589 A1	07/08/2004	WIPO				
	153.	WO 2004/057590 A1	07/08/2004	WIPO				
	154.	WO 2005/054953 A2	06/16/2005	WIPO				
OTHER DOCUMENTS								
Examiner Initials	Cite No.	(Including Author, Title, Date, Pertinent Pages, etc.)						
EXAMINER							DATE CONSIDERED	
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								

Form PTO-1449 (REV. 1/06)		US Dept. of Commerce PATENT & TRADEMARK OFFICE	ATTY DOCKET NO. 127874	APPLICATION NO. 10/588,029
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)				
		APPLICANT Yuichi SHIBAZAKI		
		FILING DATE August 1, 2006		

U.S. PATENT DOCUMENTS				
Examiner Initials	Cite No.	Document Number	Date	Name

FOREIGN PATENT DOCUMENTS						
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract	With English Translation
	155.	WO 2005/054955 A2	06/16/2005	WIPO		
	156.	WO 2005/062128 A2	07/07/2005	WIPO		
	157.	WO 2005/059617 A2	06/30/2005	WIPO		
	158.	WO 2005/059654 A1	06/30/2005	WIPO		
	159.	WO 2005/059645 A2	06/30/2005	WIPO		
	160.	WO 2005/059618 A2	06/30/2005	WIPO		
	161.	WO 2005/064405 A2	07/14/2005	WIPO		
	162.	WO 2005/064400 A2	07/14/2005	WIPO		
	163.	WO 2005/069055 A2	07/28/2005	WIPO		
	164.	WO 2005/069081 A2	07/28/2005	WIPO		
	165.	WO 2005/071491 A2	08/04/2005	WIPO		
	166.	WO 2005/074606 A2	08/18/2005	WIPO		
	167.	WO 2005/076084 A1	08/18/2005	WIPO		
	168.	WO 2005/081067 A1	09/01/2005	WIPO		
	169.	WO 2005/081030 A1	09/01/2005	WIPO		
	170.	WO 2005/069078 A1	07/28/2005	WIPO		
	171.	WO 2005/050324 A2	06/02/2005	WIPO		
	172.	WO 2005/098504 A1	10/20/2005	WIPO		
	173.	WO 2005/098505 A1	10/20/2005	WIPO		
	174.	WO 2005/098506 A1	10/20/2005	WIPO		

OTHER DOCUMENTS		
Examiner Initials	Cite No.	(Including Author, Title, Date, Pertinent Pages, etc.)

EXAMINER	DATE CONSIDERED
Examiner:	Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Form PTO-1449 (REV. 1/06)		US Dept. of Commerce PATENT & TRADEMARK OFFICE	ATTY DOCKET NO. 127874	APPLICATION NO. 10/588,029
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)		APPLICANT Yuichi SHIBAZAKI		
		FILING DATE August 1, 2006		

U.S. PATENT DOCUMENTS				
Examiner Initials	Cite No.	Document Number	Date	Name

FOREIGN PATENT DOCUMENTS						
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract	With English Translation
	175.	WO 2005/106589 A1	11/10/2005	WIPO		
	176.	WO 2005/111722 A2	11/24/2005	WIPO		
	177.	WO 2005/111689 A2	11/24/2005	WIPO		
	178.	WO 2005/119368 A2	12/15/2005	WIPO		
	179.	WO 2005/119369 A1	12/15/2005	WIPO		
	180.	WO 2005/001572 A2	01/06/2005	WIPO		
	181.	WO 2005/048328 A1	5/26/2005	WIPO		
	182.	WO 2005/062351 A1	7/7/2005	WIPO		
	183.	WO 2005/010611 A2	2/3/2005	WIPO		
	184.	WO 98/40791	9/17/1998	WIPO		
	185.	WO 2004/019128 A2	3/4/2004	WIPO		
	186.	WO 99/49504	9/30/1999	WIPO	X	X
	187.	EP I 041 357 A1	10/4/2000	Europe		
	188.	EP I 420 299 A2	5/19/2004	Europe		
	189.	DD 221 563 A1	9/14/1983	Germany	X	X
	190.	DE 224 448 A1	7/3/1985	Germany	X	X
	191.	JP A 2000-511704	9/5/2000	Japan	X	X
	192.	JP A 2000-164504	6/16/2000	Japan	X	X
	193.	JP A 2004-289128	10/14/2004	Japan	X	X

OTHER DOCUMENTS						
Examiner Initials	Cite No.	(Including Author, Title, Date, Pertinent Pages, etc.)				

EXAMINER	DATE CONSIDERED
Examiner:	Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Form PTO-1449 (REV. 1/06)		US Dept. of Commerce PATENT & TRADEMARK OFFICE	ATTY DOCKET NO. 127874	APPLICATION NO. 10/588,029
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)		APPLICANT Yuichi SHIBAZAKI		
		FILING DATE August 1, 2006		

U.S. PATENT DOCUMENTS				
Examiner Initials	Cite No.	Document Number	Date	Name

FOREIGN PATENT DOCUMENTS						
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract	With English Translation
	194.	JP A 6-124873	5/6/1994	Japan	X	X
	195.	JP A 4-305915	10/28/1992	Japan	X	
	196.	JP A 4-305917	10/28/1992	Japan	X	
	197.	JP A 5-62877	3/12/1993	Japan	X	X
	198.	JP A 7-220990	8/18/1995	Japan	X	X
	199.	JP A 8-316125	11/29/1996	Japan	X	X
	200.	JP A 10-303114	11/13/1998	Japan	X	X
	201.	JP A 10-340846	12/22/1998	Japan	X	X
	202.	JP A 11-176727	7/2/1999	Japan	X	X
	203.	JP A 58-202448	11/25/1983	Japan	X	X
	204.	JP A 59-19912	2/1/1984	Japan	X	X
	205.	JP A 62-65326	3/24/1987	Japan	X	X
	206.	JP A 63-157419	6/30/1988	Japan	X	X
	207.	JP A 2000-58436	2/25/2000	Japan	X	X
	208.	JP A 57-153433	9/22/1982	Japan	X	X

OTHER DOCUMENTS		
Examiner Initials	Cite No.	(Including Author, Title, Date, Pertinent Pages, etc.)

EXAMINER	DATE CONSIDERED
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

Form PTO-1449 (REV. 1/06) INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)			US Dept. of Commerce PATENT & TRADEMARK OFFICE	ATTY DOCKET NO. 127874	APPLICATION NO. 10/588,029
			APPLICANT Yuichi SHIBAZAKI		
			FILING DATE August 1, 2006		
U.S. PATENT DOCUMENTS					
Examiner Initials	Cite No.	Document Number	Date	Name	
FOREIGN PATENT DOCUMENTS					
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract
OTHER DOCUMENTS					
Examiner Initials	Cite No.	(Including Author, Title, Date, Pertinent Pages, etc.)			
	209.	Lin, B.J. "Semiconductor Foundry, Lithography, and Partners." Proceedings of SPIE, Vol. 4688, pp. 11 - 24, 2002.			
	210.	Switkes, M., et al. "Resolution Enhancement of 157nm Lithography by Liquid Immersion." Proceedings of SPIE, Vol. 4691, pp. 459 - 465, 2002.			
	211.	Switkes, M., et al. "Resolution Enhancement of 157nm Lithography by Liquid Immersion." J. Microlith., Microfab., Microsyst., Vol. 1, No. 3, pp. 1 - 4, 2002.			
	212.	Owa, Soichi, et al. "Nikon F2 Exposure Tool," slides 1 - 25, 3 rd 157nm Symposium, September 4, 2002.			
	213.	Owa, Soichi. "Immersion Lithography," slides 1 - 24, Immersion Lithography Workshop, December 11, 2002.			
	214.	Owa, Soichi, et al. "Immersion Lithography; its Potential Performance and Issues." Proceedings of SPIE, Vol. 5040, pp. 724 - 733, 2003.			
	215.	Owa, Soichi, et al. "Potential Performance and Feasibility of Immersion Lithography," slides 1 - 33, NGL Workshop 2003, July 2003.			
	216.	Owa, Soichi, et al. "Update on 193nm Immersion Exposure Tool," slides 1 - 38, Immersion Workshop 2004, January 27, 2004.			
	217.	Owa, Soichi, et al. "Update on 193nm Immersion Exposure Tool," slides 1 - 51, Litho Forum, January 28, 2004.			
EXAMINER					DATE CONSIDERED
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.					

Date: January 5, 2007